

PCTWORLD INTELLECTUAL PROPERTY ORGANIZATION
International Bureau1PDS
200106388-2

INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

(51) International Patent Classification 7 :

B01D 46/00

A1*

(11) International Publication Number:

WO 00/64562

(43) International Publication Date:

2 November 2000 (02.11.00)

(21) International Application Number: PCT/US00/11736

(22) International Filing Date: 28 April 2000 (28.04.00)

(30) Priority Data:

60/131,461

28 April 1999 (28.04.99)

US

(71) Applicant (for all designated States except US): STRA-
TOTECH CORPORATION [US/US]; 5441 Boeing Drive,
Suite 1B, Loveland, CO 80538 (US).

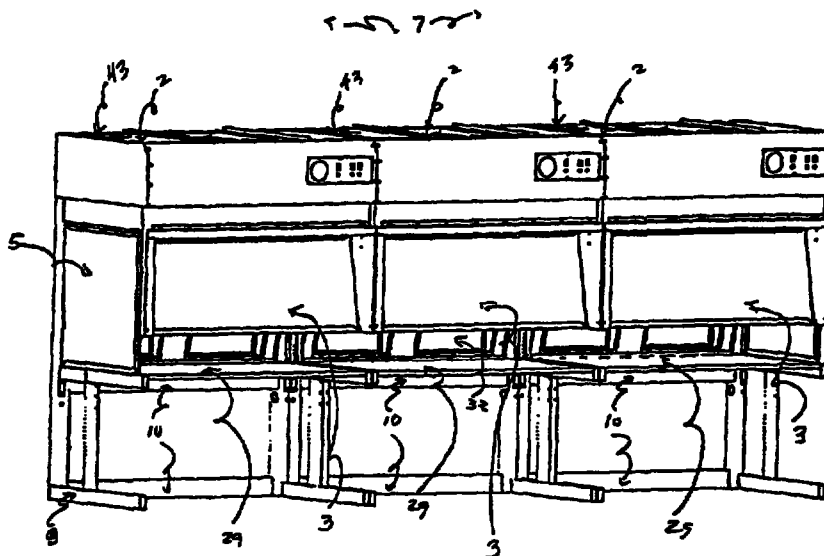
(72) Inventors; and

(75) Inventors/Applicants (for US only): SIEMERS, Warren, G.
[US/US]; 8038 Allott Avenue, Fort Collins, CO 80525
(US). HAMOR, Gary, D. [US/US]; 11158 North 66th Street,
Longmont, CO 80503 (US).(74) Agent: MILES, Craig, R.; Santangelo Law Offices, P.C., Third
Floor, 125 South Howes, Fort Collins, CO 80521 (US).(81) Designated States: AE, AL, AM, AT, AT (Utility model), AU,
AZ, BA, BB, BG, BR, BY, CA, CH, CN, CR, CU, CZ, CZ
(Utility model), DE, DE (Utility model), DK, DK (Utility
model), DM, EE, EE (Utility model), ES, FI, FI (Utility
model), GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS,
JP, KE, KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV,
MA, MD, MG, MK, MN, MW, MX, NO, NZ, PL, PT, RO,
RU, SD, SE, SG, SI, SK, SK (Utility model), SL, TJ, TM,
TR, TT, TZ, UA, UG, US, UZ, VN, YU, ZA, ZW, ARIPO
patent (GH, GM, KE, LS, MW, SD, SL, SZ, TZ, UG, ZW),
Eurasian patent (AM, AZ, BY, KG, KZ, MD, RU, TJ, TM),
European patent (AT, BE, CH, CY, DE, DK, ES, FI, FR,
GB, GR, IE, IT, LU, MC, NL, PT, SE), OAPI patent (BF,
BJ, CF, CG, CI, CM, GA, GN, GW, ML, MR, NE, SN,
TD, TG).

Published

With international search report.

(54) Title: ADJUSTABLE CLEAN-AIR FLOW ENVIRONMENT



(57) Abstract

Enclosures having adjustable clean gas flow environments and methods of enclosed pressure differential distribution technology. Specifically, clean gas flow enclosures, which provide for the isolation of materials from airborne micro-particulate contamination. An embodiment of the invention utilizes a small footprint, modular, selectable, clean-gas flow environment for handling and isolating materials. The environment can be a clean room class environment by providing filtered gas from a gas flow generator (12) through a gas filter (13) to a filtered gas flow space (20). An embodiment of the invention provides a first plenum (23) and a second plenum (26) so that both a horizontal filtered gas flow and vertical filtered gas flow may be used separately or in combination within the same filtered gas flow space (20).